

From: [Jamie Phillips](#)
To: [Campbell, Joseph - 0552 - MITLL](#)
Cc: [Rothschild, Mordechai - 0800 - MITLL](#)
Subject: Re: IEEE Milestone for "Development of 193-nm Projection Photolithography"
Date: Wednesday, April 20, 2022 3:09:52 PM

Dear Joe,

I very much support the IEEE Milestone Award proposal on the *Development of 193-nm Projection Photolithography*. This was clearly an outstanding contribution and technical milestone!

Best Regards,
Jamie

On Wed, Apr 20, 2022 at 2:07 PM Campbell, Joseph - 0552 - MITLL <jpc@ll.mit.edu> wrote:

Dear Prof. Jamie Phillips,

Following up on my email with Ravi M. Todi (EDS ExCom President) and his support, we would appreciate your support for an IEEE Milestone Award proposal on the *Development of 193-nm Projection Photolithography*:

MIT Lincoln Laboratory pioneered R&D, engineering, testing, and demonstration of 193-nm projection lithography, the semiconductor manufacturing technology that has since become mainstream worldwide. During 1984–1996, Lincoln Laboratory became an international center of excellence, which, in collaboration with industrial partners and consortia, helped guide early-stage semiconductor manufacturing with 193 nm and paved the way to widespread adoption of this technology.

The IEEE EDS Optoelectronic Devices Technical Committee would likely be considered the subject matter experts in the field of this proposal (attached). We would be most grateful for your support from a technical perspective. If you agree, could you please reply stating that you support MIT Lincoln Laboratory's IEEE Milestone Award proposal on the *Development of 193-nm Projection Photolithography*?

Kind regards,

Joe

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Joseph P. Campbell, PhD, FIEEE

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